EECS 143
Microfabrication
Technology

Expected MEMS data

Unreleased Bimorph I-V Curve

Expected (released) Bimorph I-V curve
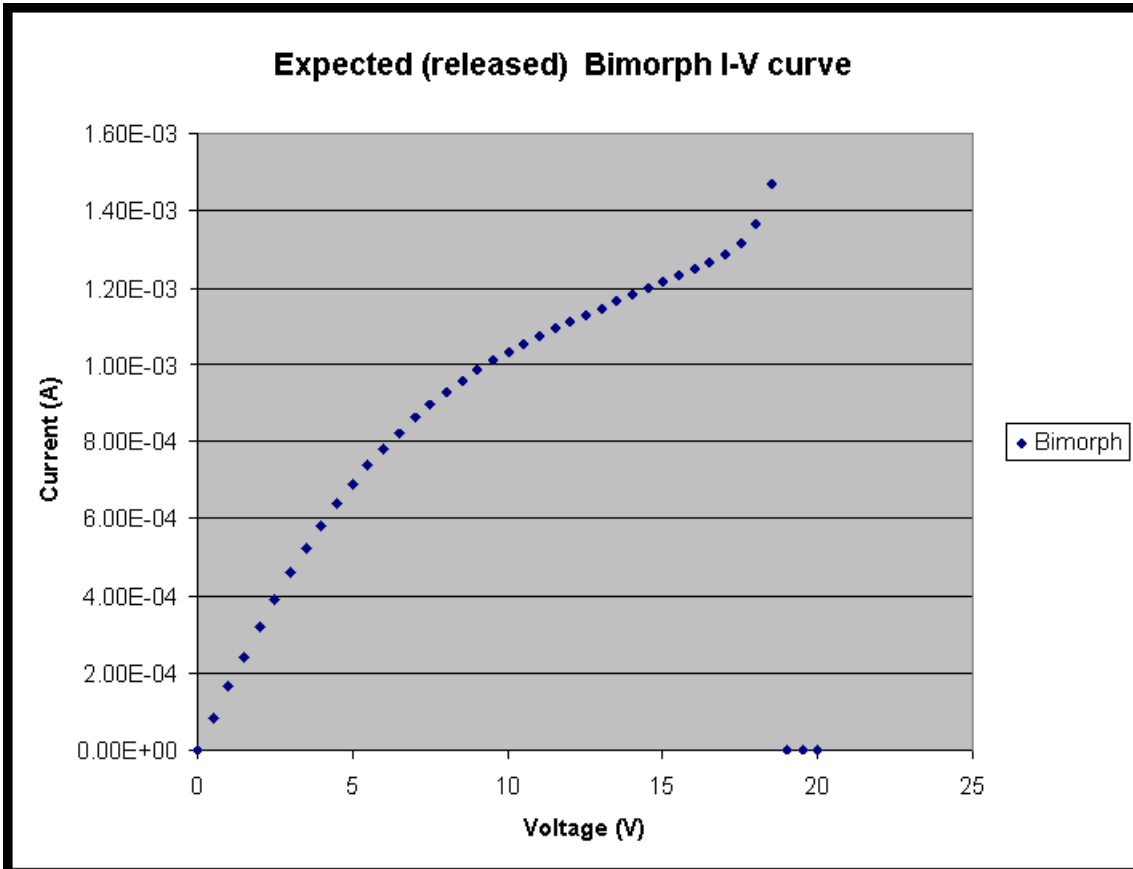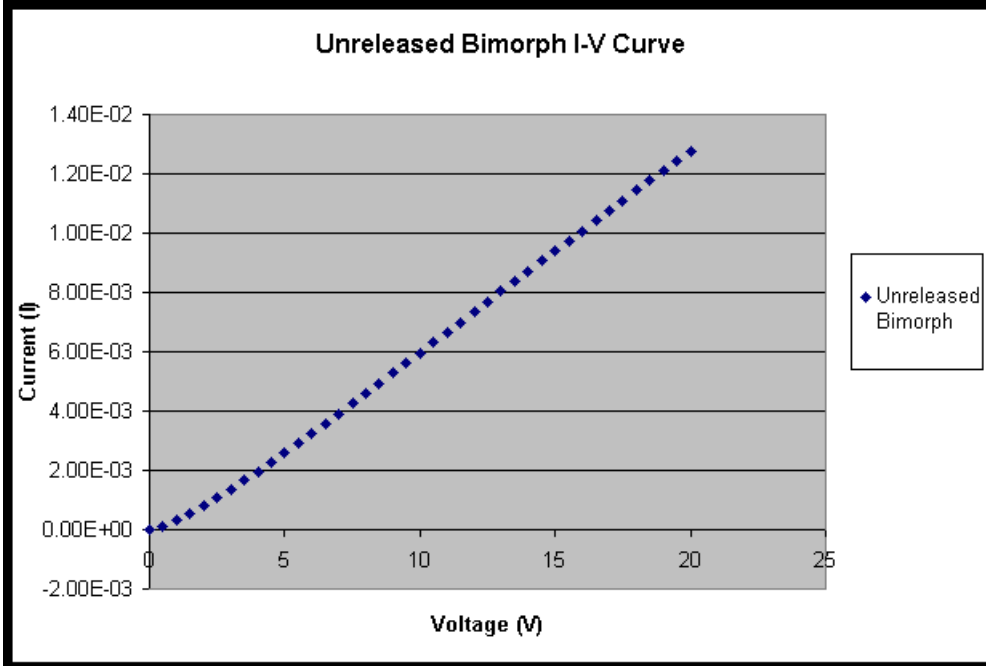
Expected Cantilever I-V Data